Title (en)

Electron source providing a particle retention device.

Title (de)

Elektronenquelle mit teilchenhaltender Anordnung.

Title (fr)

Source d'électrons présentant un dispositif de rétention de matières.

Publication

EP 0480518 B1 19950201 (FR)

Application

EP 91202587 A 19911003

Priority

FR 9012613 A 19901012

Abstract (en)

[origin: JPH04274149A] PURPOSE: To separate most suitably plasma from extraction region electrically by a vacuum arc electron source with a plasma generator, wherein an anode and a cathode are arranged facing each other to generate plasma when adding appropriate electric potential between the anode and the cathode, a plasma extraction device and a substance holding device arranged between the electron extraction device and the plasma generator. CONSTITUTION: One or more conductive upstream baffles 10 and downstream baffles 20 are composed with a substance holding device arranged in the direction of electron extraction, and these baffles have holes 16, 26 arranged in five-point shape and when electric potential of these baffles are regulated in fixed values, plasma P is controlled so as not to extend to the downside of the downstream baffle 20.

IPC 1-7

H01J 3/02

IPC 8 full level

G21K 1/00 (2006.01); **H01J 3/02** (2006.01); **H01J 37/077** (2006.01)

CPC (source: EP US)

H01J 3/025 (2013.01 - EP US)

Cited by

EP0810628A3

Designated contracting state (EPC)

DE FR GB

DOCDB simple family (publication)

EP 0480518 A1 19920415; **EP 0480518 B1 19950201**; DE 69107162 D1 19950316; DE 69107162 T2 19950831; FR 2667980 A1 19920417; JP H04274149 A 19920930; US 5256931 A 19931026

DOCDB simple family (application)

EP 91202587 A 19911003; DE 69107162 T 19911003; FR 9012613 A 19901012; JP 26228491 A 19911009; US 77565491 A 19911010